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XA-9387
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Group Art Unit: 2877

Appln. No.: 09/714,183

Filed: November 17, 2000

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING THE SAME MEASURING METHOD, AND EXPOSURE METHOD

* * *

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Pursuant to 37 C.F.R. § 1.56, and without any assertion as to materiality or prior art effect, the documents listed on the attached Form PTO-1449 are hereby cited.

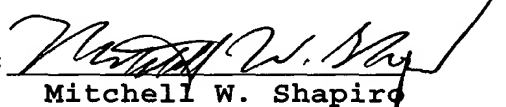
Documents AA, AB, and AL-AO are cited in the International Search Report (copy attached) in the parent PCT application.

Respectfully submitted,

MWS:pdh

Miles & Stockbridge P.C.
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Suite 500
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April 11, 2001

By:


Mitchell W. Shapiro
Reg. No. 31,568

FORM PTO-1449

Atty. Docket No.

Appln. No.

XA-9387

09/714,183

LIST OF DOCUMENTS CITED BY APPLICANT

Applicant

Hitoshi TAKEUCHI

Filing Date

November 17, 2000

Group

2877

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Sub-class	Filing Date
AA	5,680,200	10/21/97	Sugaya et al.	355	53	
AB	5,754,299	5/19/98	Sugaya et al.	356	401	
AC	5,825,476	10/20/98	Abitol et al.	356	124	
AD	5,233,174	8/3/93	Zmek	250	201.9	
AE	5,864,381	1/26/99	Neal et al.	351	205	
AF	5,936,720	8/10/99	Neal et al.	356	121	
AG	5,493,391	2/20/96	Neal et al.	356	121	
AH	4,737,621	4/12/88	Gonsiorowski et al.	250	201	
AI	4,490,039	12/25/84	Bruckler et al.	356	121	
AJ	5,629,765	5/13/97	Schmutz	356	121	
AK	5,912,731	6/15/99	DeLong et al.	356	121	

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Sub-Class	Translation
AL	2-238338	9/20/90	Japan			Yes
AM	9-49781	2/18/97	Japan			No
AN	10-92722	4/10/98	Japan			No
AO	0 833 193 A	1/4/98	Europe			
AP						
AQ						

OTHER (including author, title, date, pertinent pages, etc.)

AR	
AS	

Examiner

Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA	6,052,180	4/18/00	Neal et al.	356	121	
	AB	6,130,419	10/10/00	Neal	250	201.9	
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

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	AO						
	AP						
	AQ						

OTHER (including author, title, date, pertinent pages, etc.)

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	AS	

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